PATENT ATY. DKL AMAT/S819/DSM/BCVD/JW

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re Application of:

Suzuki, et al.

Serial No.: 10/004,489

Confirmation No.: 9428

Filed:

October 23, 2001

For:

Method of Forming Film, Method of Manufacturing Semiconductor Device and Film Forming Apparatus

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Group Art Unit: 2818

Examiner: Renee R. Berry

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OFFICE OF PETITIONS

MAIL STOP 313(c) Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

## CERTIFICATE OF FACSIMILE TRANSMISSION UNDER 37 CFR 1.8

I hereby certify that this correspondence and the documents referred to as attached therein are being facsimile transmitted to the U.S. Patent and Trademark Office to the fax number Indicated by the Examiner, namely, fax number 571-273-0025 to the attention of the named Examiner, on the date below.

## EXPRESS ABANDONMENT AFTER PAYMENT OF ISSUE FEE

Applicants hereby request that the referenced application be expressly abandoned.

Respectfully submitted,

Keith M. Tackett

Registration No. 32,008

MOSER, PATTERSON & SHERIDAN, L.L.P.

3040 Post Oak Blvd., Suite 1500

Houston, TX 77056

Telephone: (713) 623-4844 Facsimile: (713) 623-4846 Attorney for Applicant(s)